## **CLAIMS**

What is claimed is:

1. A MEMS anchor system for securing a base of a MEMS device to a substrate, comprising:

a plurality of anchors securing the base of the MEMS device to the substrate.

- 2. The MEMS anchor system of claim 1, wherein each anchor comprises a plurality of anchor legs, each anchor leg being attached at one end to the base of the MEMS device and attached at another end to the substrate.
- 3. The MEMS anchor system of claim 2, wherein the plurality of anchor legs comprises a first number of anchor legs that are orientated along a first direction, a second number of anchor legs that are orientated along a second direction, and the first number of anchor legs are stronger and longer than the second number of anchor legs.
- 4. The MEMS anchor system of claim 3, wherein the first number of anchor legs orientated along the first direction has a length that is at least twice the length of the second number of anchor legs orientated along the second direction.
- 5. The MEMS anchor system of claim 1, wherein the plurality of anchors are arranged in at least two rows, each row comprising at least two anchors.
  - 6. The MEMS anchor system of claim 5, wherein each row comprises at least four anchors.

20

- 7. The MEMS anchor system of claim 1, wherein the plurality of anchors comprises at least eight anchors.
- 5 8. A MEMS apparatus, comprising:
  - a beam;
  - a base attached to one end of the beam;
  - a substrate; and
  - a plurality of anchors securing the base to the substrate.
  - 9. The MEMS apparatus of claim 8, wherein the plurality of anchors is located away from the end of the beam attached to the base.
  - 10. The MES apparatus of claim 8, wherein the width of the base is greater than the width of the beam.
  - 11. The MEM\$ apparatus of claim 8, wherein each anchor comprises a plurality of anchor legs, each anchor leg being attached at one end to the base and attached at another end to the substrate.
  - 12. The MEMS apparatus of claim 11, wherein the plurality of anchor legs comprises a first number of anchor legs that are orientated along a first direction, a second number of anchor legs

20

that are orientated along a second direction, and the first number of anchor legs are stronger and longer than the second number of anchor legs.

- 13. The MEMS anchor system of claim 12, wherein the first number of anchor legs
  5 orientated along the first direction has a length that is at least twice the length of the second number of anchor legs orientated along the second direction.
  - 14. The MEMS apparatus of claim 8, wherein the plurality of anchors are arranged in at least two rows, each row comprising at least two anchors.
  - 15. The MEMS apparatus of claim 14, wherein each row comprises at least four anchors.
  - 16. The MEMS apparatus of claim 8, wherein the plurality of anchors comprises at least eight anchors.
  - 17. The MEMS apparatus of claim 8, further comprising a folded spring attaching the one end of the beam to the base.
  - 18. The MEMS apparatus of claim 8, wherein the other end of the beam is free.
  - 19. A MEMS apparatus, comprising:

a beam;

two bases, each base attached to one end of the beam;

a substrate; and

two sets of multiple anchors, each set of multiple anchors securing one of the two bases to the substrate.

- 5 20. The MEMS apparatus of claim 19, wherein each set of multiple anchors is located away from the end of the beam attached to the respective base.
  - 21. The MEMS apparatus of claim 19, wherein the width of each one of the bases is greater than the width of the beam.
  - 22. The MEMS apparatus of claim 19, wherein each anchor comprises a plurality of anchor legs, each anchor leg being attached at one end to the respective base and attached at another end to the substrate.
  - 23. The MEMS apparatus of claim 22, wherein the plurality of anchor legs comprises a first number of anchor legs that are orientated along a first direction, a second number of anchor legs that are orientated along a second direction, and the first number of anchor legs are stronger and longer than the second number of anchor legs.
- 24. The MEMS anchor system of claim 23, wherein the first number of anchor legs orientated along the first direction has a length that is at least twice the length of the second number of anchor legs orientated along the second direction.

- 25. The MEMS apparatus of claim 19, wherein each set of multiple anchors is arranged in at least two rows of anchors, each row comprising at least two anchors.
- 5 26. The MEMS apparatus of claim 25, wherein each row comprises at least four anchors.
  - 27. The MEMS apparatus of claim 19, wherein each set of multiple anchors comprises at least eight anchors.
  - 28. The MEMS apparatus of claim 19, further comprising a folded spring attaching one end of the beam to one of the two bases.

Ada A3